

Notice of References Cited	Application/Control No. 09/851,313		Applicant(s)/Patent Under Reexamination USAMI, TATSUYA	
	Examiner Julio J. Maldonado		Art Unit 2823	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,008,540	12-1999	Lu et al.	257/758
*	B	US-6,072,227	06-2000	Yau et al.	257/642
*	C	US-6,218,317 B1	04-2001	Allada et al.	438/780
*	D	US-6,277,732 B1	08-2001	Lou, Chine-Gie	438/634
*	E	US-6,333,257 B1	12-2001	Aoi, Nobuo	438/626
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
*	U	Wolf et al., Silicon Processing for the VLSI Era, Volume 1-Process Technology, 1986, Lattice Press, pages 168-174.
*	V	Chen et al., Effects of slurry formulations on chemical-mechanical polishing of low dielectric constant polysiloxanes: hydrido-organo siloxane and methyl silsesquioxane; J. Vac. Sci Technol. B 18(1), Jan/Feb 2000; pages 201-207
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.